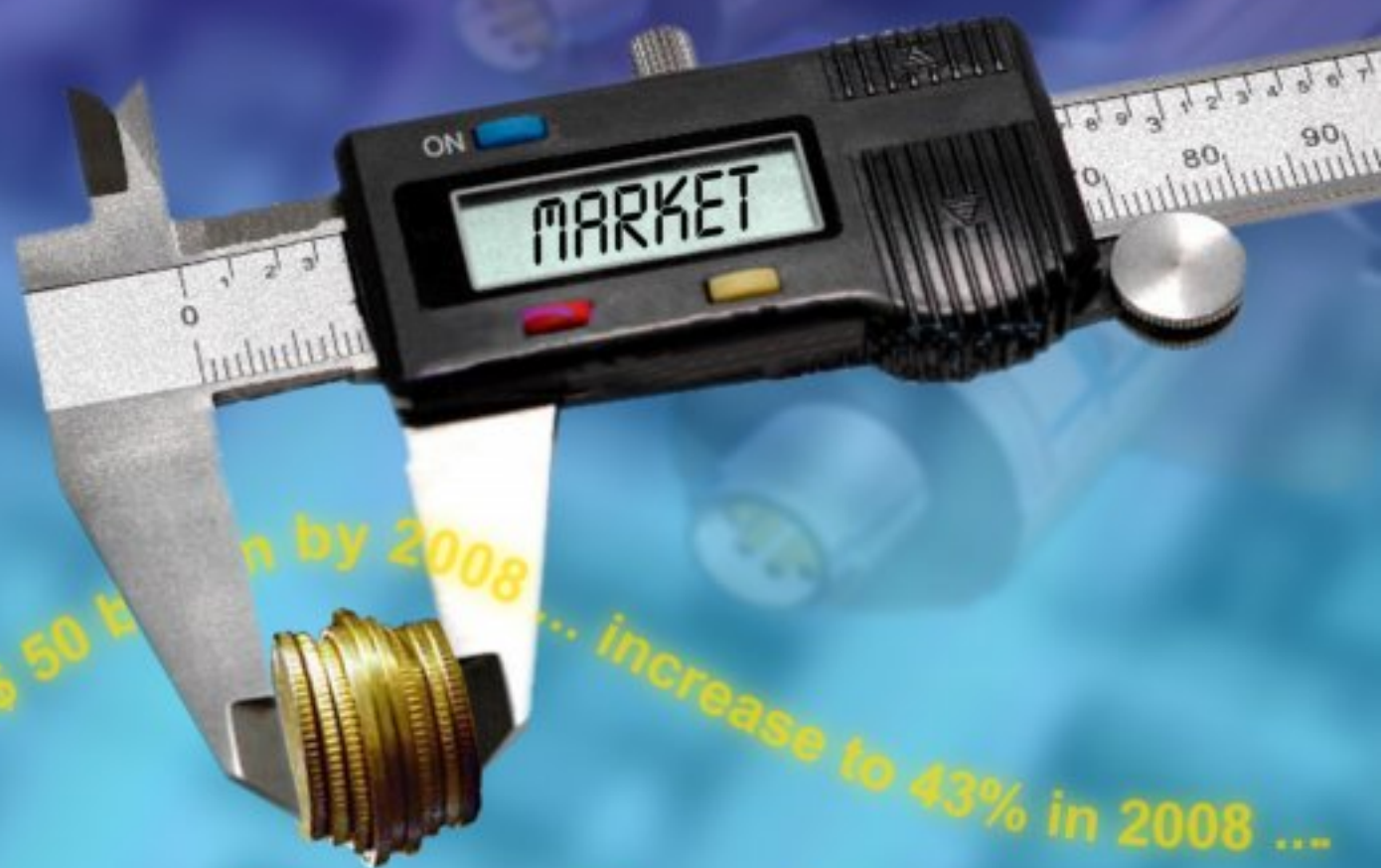


ISSN 1726-5749

SENSORS & TRANSDUCERS

12

vol. 74
/06



Sensor Market Trends

International Frequency Sensor Association Publishing





Sensors & Transducers

Volume 74
Issue 12
December 2006

www.sensorsportal.com

ISSN 1726-5479

Editor-in-Chief: professor Sergey Y. Yurish, phone: +34 696067716, e-mail: editor@sensorsportal.com

Editorial Advisory Board

- Ahn, Jae-Pyoung**, Korea Institute of Science and Technology, Korea
Arndt, Michael, Robert Bosch GmbH, Germany
Atghiaee, Ahmad, University of Tehran, Iran
Augutis, Vyantas, Kaunas University of Technology, Lithuania
Avachit, Patil Lalchand, North Maharashtra University, India
Bahreyni, Behraad, University of Manitoba, Canada
Barford, Lee, Agilent Laboratories, USA
Barlingay, Ravindra, Priyadarshini College of Engineering and Architecture, India
Basu, Sukumar, Jadavpur University, India
Beck, Stephen, University of Sheffield, UK
Ben Bouzid, Sihem, Institut National de Recherche Scientifique, Tunisia
Bodas, Dhananjay, IMTEK, Germany
Bousbia-Salah, Mounir, University of Annaba, Algeria
Brudzewski, Kazimierz, Warsaw University of Technology, Poland
Cerda Belmonte, Judith, Imperial College London, UK
Chakrabarty, Chandan Kumar, Universiti Tenaga Nasional, Malaysia
Chen, Rongshun, National Tsing Hua University, Taiwan
Chiriac, Horia, National Institute of Research and Development, Romania
Chung, Wen-Yaw, Chung Yuan Christian University, Taiwan
Cortes, Camilo A., Universidad de La Salle, Colombia
Costa-Felix, Rodrigo, Inmetro, Brazil
Cusano, Andrea, University of Sannio, Italy
D'Amico, Arnaldo, Università di Tor Vergata, Italy
Dickert, Franz L., Vienna University, Austria
Dieguez, Angel, University of Barcelona, Spain
Ding Jian, Ning, Jiangsu University, China
Donato, Nicola, University of Messina, Italy
Donato, Patricio, Universidad de Mar del Plata, Argentina
Dong, Feng, Tianjin University, China
Drljaca, Predrag, Instersema Sensoric SA, Switzerland
Erdem, Gursan K. Arzum, Ege University, Turkey
Erkmen, Aydan M., Middle East Technical University, Turkey
Estrada, Horacio, University of North Carolina, USA
Fericean, Sorin, Balluff GmbH, Germany
Gaura, Elena, Coventry University, UK
Gole, James, Georgia Institute of Technology, USA
Gonzalez de la Ros, Juan Jose, University of Cadiz, Spain
Guan, Shan, Eastman Kodak, USA
Gupta, Narendra Kumar, Napier University, UK
Hernandez, Wilmar, Universidad Politecnica de Madrid, Spain
Homentcovschi, Dorel, SUNY Binghamton, USA
Hsiai, Tzung (John), University of Southern California, USA
Jaffrezic-Renault, Nicole, Ecole Centrale de Lyon, France
Jaime Calvo-Galleg, Jaime, Universidad de Salamanca, Spain
James, Daniel, Griffith University, Australia
Janting, Jakob, DELTA Danish Electronics, Denmark
Jiang, Liudi, University of Southampton, UK
Jiao, Zheng, Shanghai University, China
John, Joachim, IMEC, Belgium
Kalach, Andrew, Voronezh Institute of Ministry of Interior, Russia
Katake, Anup, Texas A&M University, USA
Lacnjevac, Caslav, University of Belgrade, Serbia
Li, Genxi, Nanjing University, China
Lin, Hermann, National Kaohsiung University, Taiwan
Lin, Paul, Cleveland State University, USA
Liu, Cheng-Hsien, National Tsing Hua University, Taiwan
Liu, Songqin, Southeast University, China
Lorenzo, Maria Encarnacio, Universidad Autonoma de Madrid, Spain
Matay, Ladislav, Slovak Academy of Sciences, Slovakia
Mekid, Samir, University of Manchester, UK
Mi, Bin, Boston Scientific Corporation, USA
Moghavvemi, Mahmoud, University of Malaya, Malaysia
Mohammadi, Mohammad-Reza, University of Cambridge, UK
Mukhopadhyay, Subhas, Massey University, New Zealand
Neelamegam, Periasamy, Sastra Deemed University, India
Neshkova, Milka, Bulgarian Academy of Sciences, Bulgaria
Oberhammer, Joachim, Royal Institute of Technology, Sweden
Ohyama, Shinji, Tokyo Institute of Technology, Japan
Pereira, Jose Miguel, Instituto Politecnico de Seteabal, Portugal
Petsev, Dimitir, University of New Mexico, USA
Pogacnik, Lea, University of Ljubljana, Slovenia
Pratepasen, Asa, Kingmoungut's University of Technology, Thailand
Pullini, Daniele, Centro Ricerche FIAT, Italy
Pumera, Martin, National Institute for Materials Science, Japan
Rajanna, K., Indian Institute of Science, India
Reig, Candid, University of Valencia, Spain
Robert, Michel, University Henri Poincare, France
Rodriguez, Angel, Universidad Politecnica de Catalunya, Spain
Rothberg, Steve, Loughborough University, UK
Royo, Santiago, Universitat Politecnica de Catalunya, Spain
Sadana, Ajit, University of Mississippi, USA
Sapozhnikova, Ksenia, D.I.Mendeleyev Institute for Metrology, Russia
Saxena, Vibha, Bhabha Atomic Research Centre, Mumbai, India
Shearwood, Christopher, Nanyang Technological University, Singapore
Shin, Kyuho, Samsung Advanced Institute of Technology, Korea
Shmaliy, Yuriy, Kharkiv National University of Radio Electronics, Ukraine
Silva Girao, Pedro, Technical University of Lisbon Portugal
Slomovitz, Daniel, UTE, Uruguay
Stefan-van Staden, Raluca-Ioana, University of Pretoria, South Africa
Sysoev, Victor, Saratov State Technical University, Russia
Thumbavanam Pad, Kartik, Carnegie Mellon University, USA
Tsiantos, Vassilios, Technological Educational Institute of Kaval, Greece
Twomey, Karen, University College Cork, Ireland
Vaseashta, Ashok, Marshall University, USA
Vigna, Benedetto, STMicroelectronics, Italy
Vrba, Radimir, Brno University of Technology, Czech Republic
Wandelt, Barbara, Technical University of Lodz, Poland
Wang, Liang, Advanced Micro Devices, USA
Wang, Wei-Chih, University of Washington, USA
Woods, R. Clive, Louisiana State University, USA
Xu, Tao, University of California, Irvine, USA
Yang, Dongfang, National Research Council, Canada
Ymeti, Aurel, University of Twente, Netherland
Zeni, Luigi, Second University of Naples, Italy
Zhou, Zhi-Gang, Tsinghua University, China
Zourob, Mohammed, University of Cambridge, UK

Contents

Volume 74
Issue 12
December 2006

www.sensorsportal.com

ISSN 1726-5479

Research Articles

Monitoring of High Pressure with Fiber Optic Sensor <i>Pandey N.K., Yadav B.C., Tripathi Anupam.....</i>	834
Experimental Validation of Fluorescence Intensity Ratio /Fluorescence Lifetime Temperature Sensing Technique <i>Vineet Kumar Rai and S. B. Rai.....</i>	839
Sensors and Methods for Electromagnetic Pulse Identification <i>Pavel Fiala, Petr Drexler.....</i>	844
Characterization Technique of an Excited Solid-State Piezoelectric Transformer as a Function of Transient Time <i>Selemeni Seif.....</i>	855
Methanol Sensing Behavior of Strontium(II) Added MgAl₂O₄ Composites Through Solid-State Electrical Conductivity Measurements <i>Judith Vijaya, L. John Kennedy, G. Sekaran, K.S. Nagaraja.....</i>	864
Surface Activated ZnO Thick Film Resistors for LPG Gas Sensing <i>D.R. Patil, L.A. Patil, G.H. Jain, M.S. Wagh, S.A. Patil.....</i>	874

Authors are encouraged to submit article in MS Word (doc) and Acrobat (pdf) formats by e-mail: editor@sensorsportal.com
Please visit journal webpage with preparation instruction: <http://www.sensorsportal.com/HTML/DIGEST/Submission.htm>



Surface Activated ZnO Thick Film Resistors for LPG Gas Sensing

D.R. PATIL, L.A. PATIL *, G.H. JAIN, M.S. WAGH, S.A. PATIL

Materials Research Lab, Pratap College, Amalner, 425 401, INDIA

*Corresponding author Tel.:+91-02587-224226

E-mail: plalchand_phy_aml@yahoo.co.in

Received: 1 July 2006 /Accepted: 26 December 2006 /Published: 29 December 2006

Abstract: The CuO-modified films obtained by dipping pure ZnO thick films into an aqueous solution of copper chloride for different intervals of time and fired at 500°C for 24 h. The copper chloride would transform into copper oxide upon firing. CuO-modified (0.4092 mass % CuO) ZnO thick films resulted in LPG gas detector. Upon exposure to 1000 ppm LPG gas, the barrier height between CuO-ZnO grains decreases markedly leading to a drastic decrease in resistance. An exceptional sensitivity was found to LPG gas at 400°C and no cross sensitivity was observed to other hazardous and polluting gases. The instant response (~ 5 sec) and fast recovery (~ 10 sec) are the main features of this sensor. The effects of microstructure and surfactant concentration on the gas response, selectivity, response time and recovery time of the sensor in the presence of LPG gas were studied and discussed.

Keywords: Zinc oxide, CuO-modified ZnO, LPG gas sensor, gas response and recovery time.

1. Introduction

Liquefied Petroleum Gas (LPG) is highly inflammable gas. It is explosively utilized in industrial and domestic fields as fuel. It is referred as town or cooking gas. Cooking gas consists chiefly of butane (55-vol %) [1], a colorless and odorless gas. It is usually mixed with compounds of sulfur (methyl mercaptan and ethyl mercaptan) having foul smell, so that its leakage can be noticed easily. This gas is potentially hazardous because explosion accidents might be caused when it leak out by mistake. It has been reported that, at the concentration up to noticeable leakage, it is very much more than the lower explosive limit LEL of the gas in air. So there is a great demand and emerged challenges [2] for monitoring it for the purpose of

control and safety applications in domestic and industrial fields. ZnO crystallizes in a wurtzite structure showing n-type semiconductivity [3, 4]. ZnO utilized in wide range of applications [5-11].

The aim of the present work is to develop the sensor by modifying ZnO thick films, which could be able to detect the LPG gas. Among the various metal oxide additives tested, CuO in ZnO is outstanding in promoting the sensing properties to LPG in air.

2 Experimental

2.1 Thick film preparation

AR grade (99.9 % pure) zinc oxide powder was ball milled to ensure sufficiently fine particle size. The fine powder was calcined at 1100⁰C for 24 h, in air and re-ground. Thick films of, so obtained powder, were prepared by adopting the procedure explained elsewhere [12, 13].

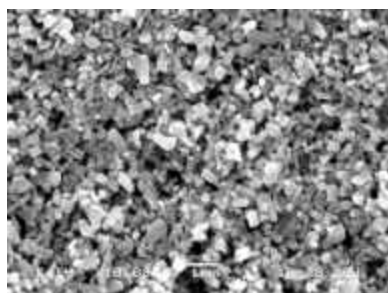
2.2 Characterization

The microstructure and chemical composition of the films were analyzed using a scanning electron microscope (JOEL JED 2300) coupled with an energy dispersive spectrometer (6360 LA). Thickness measurements were carried out using a Taylor-Hobson (Talystep, UK) system. Electrical and gas sensing characteristics were measured using a static gas sensing system.

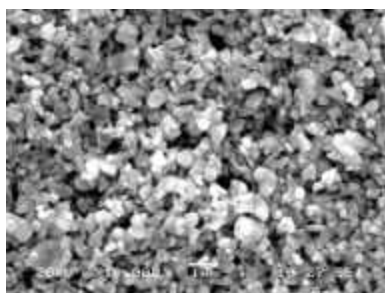
3. Materials Characterization

3.1 Microstructure-SEM

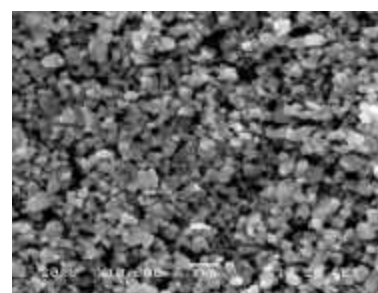
Figs.1 (a-c) depict the microstructure of unmodified ZnO, CuO-modified ZnO for 5 min and 30 min respectively. Fig. 1(a) consists of randomly distributed grains with larger size and shape distribution. Fig.1 (b) consists of CuO grains with smaller size and shape associated with the ZnO grains. CuO grains may reside in the intergranular regions of ZnO. Thus effective surface area was expected to be increased explosively. Fig.1 (c) consists of large number of smaller particles of Cu-species distributed on the surface of the ZnO film. Few Cu-species are percolated in the bulk, results in decreasing the mass % of Cu-species on the surface of the film.



(a)



(b)



(c)

Fig.1. SEM of (a) Unmodified ZnO, (b) Modified ZnO (5 min) and (c) Modified ZnO (r 30 min).

3.2 Thickness and Thermoelectric power measurements

The thicknesses of the films were observed to be in the range from 20 to 25 μm . The reproducibility of the film thickness was achieved by maintaining the proper rheology and thixotropy of the paste. The p- or n-type semi-conductivity of thick films of CuO and ZnO were confirmed by measuring thermo electromotive force of the thick film samples. The ZnO was observed to be n-type and CuO the p-type material.

3.3 Elemental analysis

Pure white ZnO is expected to be stoichiometric and showing insulating properties. The pure white ZnO powder turns yellow on calcination at higher temperature ($\sim 1100^{\circ}\text{C}$ for 24 h). It is because of deficiency of oxygen [3, 4]. Stoichiometric mass % of Zn and O in ZnO are 80.34 and 19.66 respectively. The mass % of Zn and O in each sample was not as per the stoichiometric proportion and all samples were observed to be the oxygen deficient (Table 1). This leads the non-stoichiometricity in the solid and formation of n-type semiconductor.

Table 1. Quantitative Elemental Analysis of unmodified (pure) and CuO-modified films.

Elemental Mass %	Dipping Time (min.)				
	0	2	5	15	30
Cu	0.00	0.07	0.33	0.41	0.33
O	8.06	8.77	11.30	8.11	11.18
Zn	91.95	91.16	88.38	91.48	88.49
ZnO	100	99.91	99.59	99.49	99.58
CuO	0.00	0.09	0.41	0.51	0.42
CuO-ZnO	100	100	100	100	100

4. Electrical Properties

4.1 I-V Characteristics

I-V characteristics of pure and modified ZnO are observed to be symmetrical in nature indicating ohmic nature of silver contacts. Figs.2 (a, b) depict the conductivities of pure and modified ZnO at room temperature and at 400°C .

4.2 Electrical resistivity

The semiconducting nature of ZnO is observed from the measurements of resistivity with temperature. The semiconductivity in ZnO must be due to large oxygen deficiency in it. The material would then adsorb the oxygen species at higher temperatures ($\text{O}_2^- \rightarrow 2\text{O}^- \rightarrow \text{O}^{2-}$). The adsorption chemistry of CuO-modified ZnO surface would be different from the pure ZnO thick film surface. The CuO misfits on the surface are the places where the oxygen species adsorbs.

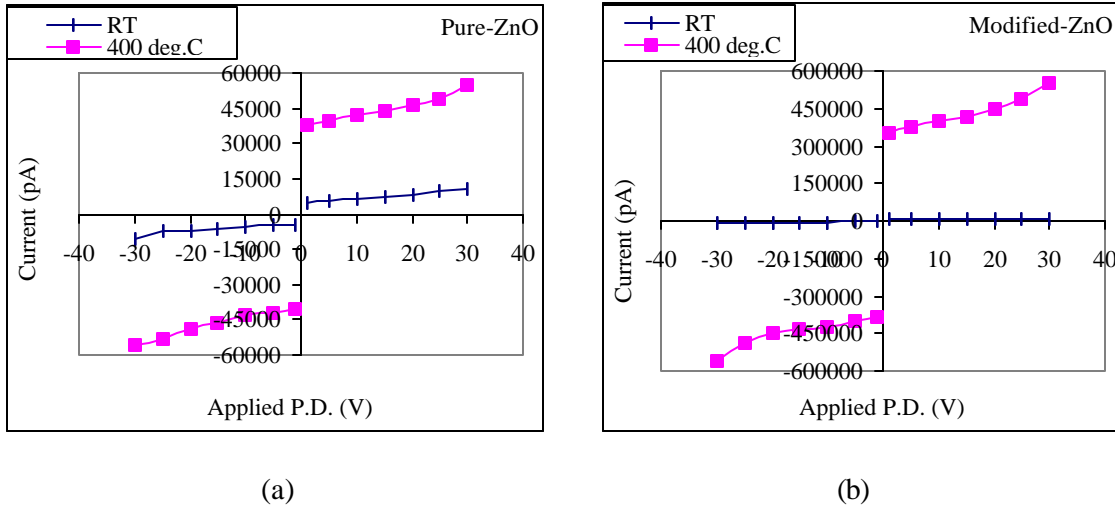
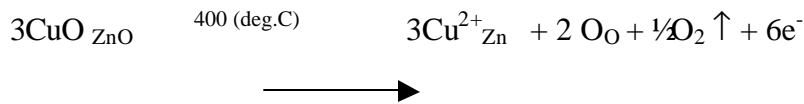


Fig.2. I-V characteristics of the sensor.

The CuO misfits distributed evenly on the surface would have made it possible to adsorb the oxygen ions even at low temperatures. From Fig.3 it is clear that, the resistivity of CuO-modified film decreases with increase in operating temperature indicating negative temperature coefficient of resistance. This behavior confirmed the semiconducting nature of modified ZnO. The drastic increase in the conductivity of CuO-modified ZnO at 400⁰C than at room temperature (Fig.2 (b)) could be attributed to the charge-carrier generation mechanism resulted from the electronic defects can be described in the Kroger-Vink [14, 15] notation as:



These generated electrons and the donor level in the energy band gap of ZnO will contribute to increase in conductivity.

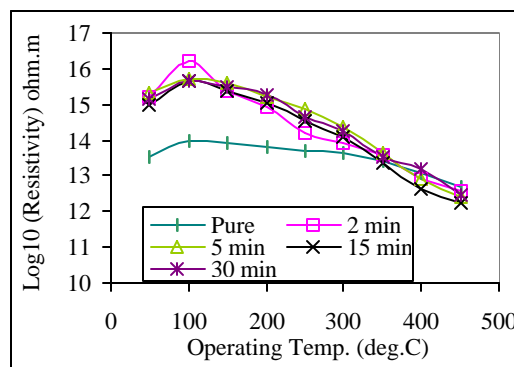


Fig.3: Variation of log (resistivity) with operating temperature.

5. Sensing Performance

5.1 Measurement of Gas response, Selectivity, Response and Recovery time

Gas response (S) is defined, as the ratio of change in conductance of the sensor on exposure of the target gas to the original conductance in air medium. The relation for S is as:

$$S = (G_g - G_a) / G_a$$

where, G_a is the conductance of sensor in air medium and G_g is the conductance of sensor in gaseous medium.

Selectivity or specificity is defined, as the ability of a sensor to respond to certain gas in the presence of more gases. Percentage selectivity factor of one gas over other is defined as, the ratio of the maximum response of other gas to the maximum response of the target gas at optimum temperature.

$$\% \text{ Selectivity factor} = (S_{\text{gas}} / S_{\text{target gas}}) \times 100 \%$$

The time taken for the sensor to attain 90 % of the maximum change in conductance on exposure to the target gas is the response time. The time taken by the sensor to get back 90 % of the original conductance is the recovery time.

5.2 Sensing performance of pure ZnO thick film

Fig. 4 depicts the variation of gas response with operating temperature of pure ZnO thick film for 1000 ppm LPG gas. In case of pure ZnO, oxygen adsorption seems to be poor which may be the result of poor response. In addition to this, ZnO requires relatively larger operating temperature to adsorb the oxygen ions, and therefore it would have responded at higher operating temperature. To improve the sensing performance of ZnO, it is essential to modify its surface.

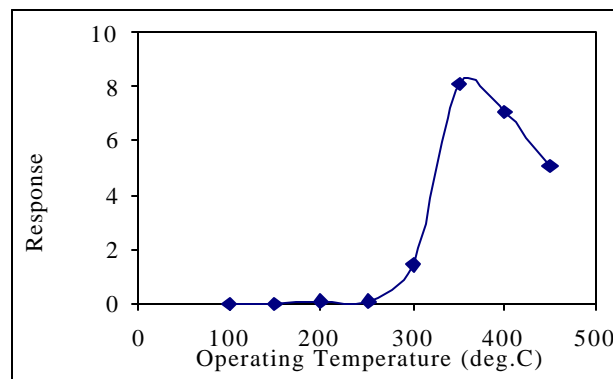


Fig. 4. Variation of response with operating temperature.

5.3 Sensing performance of CuO-modified ZnO Thick Film

5.3.1 Response and gas concentration

For CuO-modified ZnO film, the response was observed to increase continuously with increasing the gas concentration up to 1000 ppm at 400⁰C (Fig.5). The active region of the sensor would be between 100 to 1000 ppm; as the rate of rise of response is larger during this region. At lower gas concentrations, the unimolecular layer of gas molecules would be expected to be formed on the surface, which would interact with the surface more actively giving larger responses. There would be multilayers of gas molecules on the sensor surface at the higher gas concentrations resulting in saturation in response.

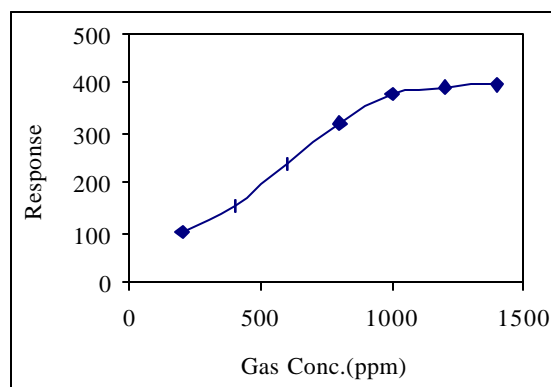


Fig.5. Variation of gas response with gas concentration.

5.3.2 Gas response, dipping time and Cu-surfactant

Fig. 6 (a, b) depict the variation of gas response with dipping time and Cu-surfactant. The film dipped for 5 min. showed highest gas response (380.25). At 5 min. dipping time, the optimum mass % of CuO (0.4092) would dispersed on the surface of the film, and mass % of oxygen was also high (11.2984) (Table 1). The highest gas response of CuO-modified ZnO would be explained as follows. The optimum mass % of CuO on the surface of ZnO would form misfit regions uniformly on the film surface. The adsorption mechanism of CuO modified ZnO would be different from pure ZnO. The number of oxygen ions adsorbed on the modified surface would be larger. Larger the number of oxygen ions adsorbed, faster and quicker would be oxidation of LPG gas. This would increase the conductance of the film drastically, enhancing gas response. It is observed from Fig.6 (b) that, the gas response is largest at 0.4092 mass % of the cu-surfactant on the surface of the film. At higher mass %, the Cu-surfactant would mask the base material-ZnO and would resist the gas to reach up to the surface sites and gas response would decrease.

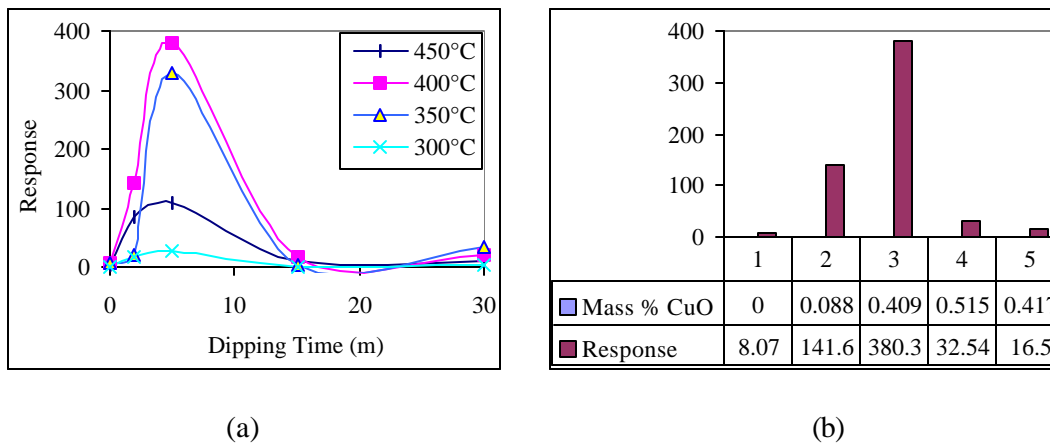


Fig. 6. Variation of gas response with (a) dipping time and (b) Cu-surfactant.

5.3.3 Gas response and operating temperature

It is clear from figure 7 that, the gas response increases with operating temperature; reaches to maximum (380.25) at 400°C, and falls with further increase in operating temperature. The LPG may burn before reaching the surface of the film at higher temperature (> 400°C). Hence, gas response may decrease above 400°C. At 400°C, larger amount of oxygen would be adsorbed on the surface, which would facilitate the sensor to oxidize the target gas (LPG) immediately giving faster and larger gas response.

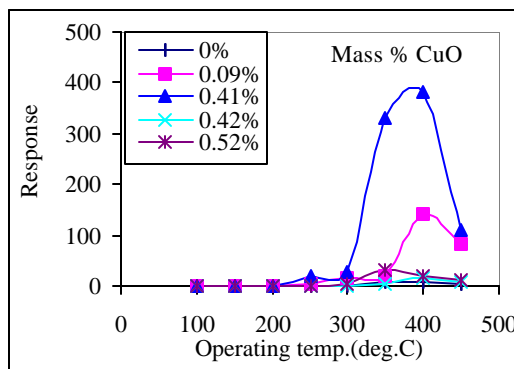


Fig. 7. Variation of gas response with operating temperature.

5.3.4 Selectivity for LPG against various gases

Fig.8 depicts the % selectivity factor of the CuO-modified ZnO (calcined at 1100°C for 24 h with 0.4092 mass % of CuO) to 1000 ppm of LPG gas against various gases at 400°C. It is clear from Fig.8 that in contrast to pure zinc oxide the sample showed not only enhanced response towards LPG but also very high selectivity.

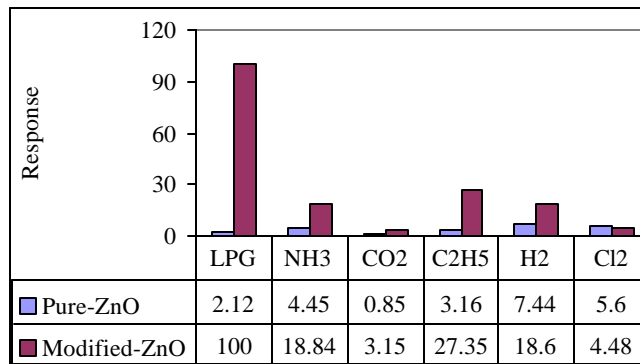


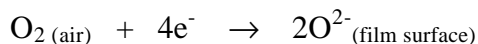
Fig.8. Gas response among various gases.

6. Discussion

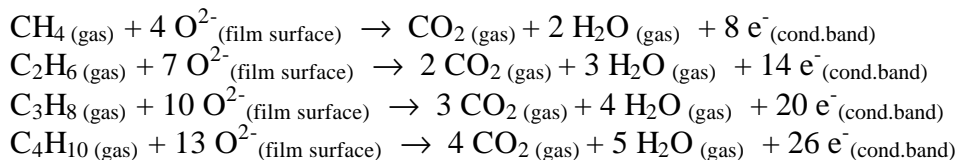
Table 2. Composition of LPG gas.

Composition (Vol %)	CH ₄	C ₂ H ₆	C ₃ H ₈	C ₄ H ₈	C ₄ H ₁₀	C ₅ H ₁₂
	6	8	11.5	15	55	4.5

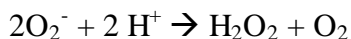
As the butane is the major constituent of LPG (Table 2), it requires high temperature to dissociate into lower alkanes. Carbon-carbon and carbon-hydrogen bonds are quite strong due to strong Vander Waals forces. They break only at higher temperatures resulting in carbon and hydrogen separation. The atmospheric oxygen O₂ adsorbs on the surface of the thick film. It captures the electrons from conduction band as:



It would result in decreasing conductivity of the film. When alkanes react with oxygen, a complex series of reactions [16-18] take place, ultimately converting the alkanes to carbon dioxide and water as:



This shows n-type conduction mechanism. At higher temperature, molecular oxygen O₂ becomes O₂⁻ and alkanes decompose producing hydrogen ions H⁺ in the reaction. The anion super-oxide O₂⁻ reacts with H⁺ giving water molecule and molecular oxygen O₂:



Catalase



LPG gas on exposure decomposes into carbon and hydrogen species, which react with adsorbed oxygen, liberating the captured electrons into conduction band resulting in enhancing the catalytic activity of the film surface.

7. Summary

From the results, following statements can be made for the sensing performance of CuO-modified sensors.

- 1) Pure zinc oxide was almost insensitive to LPG and LNG gases.
- 2) Among various additives tested CuO in ZnO is outstanding in promoting the LPG gas sensing.
- 3) Surface modification by dipping process is one of the most suitable methods of modifying the surface of thick films.
- 4) 0.4092 mass % of CuO incorporated in pure ZnO thick film is the most sensitive element to LPG gas.
- 5) CuO-modified ZnO has the potential of fabricating the LPG sensor.
- 6) The sensor showed very rapid response and recovery to LPG gas.
- 7) The sensor has good selectivity to LPG against NH₃, CO₂, Cl₂, H₂ and C₂H₅OH.

References

1. Z. Tianshu, Z. Ruifang, S. Yusheng and L. Xingqin. Influence of Sb/Fe ratio and heating temperature on microstructure and gas sensing property of Sb₂O₃-Fe₂O₃ complex oxide semi-conductors. *Sens.Actuators*, B 32 (1996) 185-189.
2. N.Yamazoe, Toward innovations of gas sensor technology (Review), *Sens. Actuators*, B 108 (2005) 2-14.
3. F.A.Cotton, G.Wilkinson, C.Murillo and M.Bochman, *Advanced Inorganic Chemistry*, (6th ed.) (2003) John Wiley and Sons (Asia) pte ltd. pp 550-570,604.
4. K.J.Laidler, *Chemical kinetics*, (2nd. ed.) TMG Publication Comp.ltd.310.
5. T.Seiyama and F.Era, Gas detecting materials, *Zairo-kagaku Jpn*, 8 (1971) 232-239.
6. W.Y. Chung, C.H. Shim, S.D. Choi and D.D. Lee. Tin oxide microsensor for LPG monitoring. *Sens.Actuators*, B 20 (1994) 139-143.
7. V.A. Chaudhary, I.S. Mulla and K. Vijayamohanan. Impedance Studies of an LPG sensor using surface ruthenated tin oxide. *Sens.Actuators*, B 55 (1999) 127-133.
8. J.Wang, M.Tona, X.Wang, Y.Ma, D. Liu, J. Wu, D. Gao and G. Du. Preparation of H₂ and LPG gas sensor. *Fuel and energy abstracts* 44-4 (2003) 259.
9. G.S.Trivikrama Rao and S.S.Madhavendra, Tin oxide based sensors for the detection of LPG, *J.mater.Sci.Lett.* 14 (1995) 529.
10. A.Srivastava, K.Jain, Rashmi, A.K.Srivastava and S.T.Laxmikumar, Study of structural and micro structural properties of SnO₂ powder for LPG and CNG gas sensors. *Mater.Chem.Phys.* 97 1-10 (2006) 85-90.
11. J.Wang, M.Tang, X. Wang, Y.Ma, D.Liu, J.Wu, D.Gao and G.Du, Preparation of H₂ and LPG gas sensor *Sens.Actuators*, B 84 2-3 (2002) 95-97.
12. M.S. Wagh, L.A. Patil, Tanay Seth, D.P.Amalnerkar. Surface cupricated SnO₂ – ZnO thick films as a H₂S gas sensor. *Mater. Chem. Phys.* 84 (2004) 228-233.
13. L.A. Patil, D.R. Patil. Heterocontact type surface cupricated SnO₂ sensor for the detection of a ppm level H₂S gas at room temperature., *Sens. Actuators* (in press).
14. C.H. Kwon, H.K. Hong, D.H. Yun, K. Lee, S.T. Kim, Y.H. Roh and B.H. Lee. Thick film Zinc Oxide gas sensor for the control of lean air-to-fuel ratio in domestic combustion systems. *Sens.Actuators*, B 24-25 (1995) 610-613.
15. P.Kofstad, *Nonstoichiometry, Diffusion and Electrical conductivity in binary metal oxides*, Wiley-interscience, New York, (1972) 15-21.

16. M. Aslam, V.A. Chaudhary, I.S. Mulla, S.R. Sainkar, A.B. Mandale, A.A. Belhekar and K. Vijayamohan. A highly selective ammonia gas sensor using surface-ruthenated zinc oxide. *Sens.Actuators*, 75 (1999) 162-167.
17. Sang-Jin Jung and Hiroaki Yanagida. The characterization of CuO/ZnO heterocontact-type gas sensor-having selectivity for CO gas. *Sens.Actuators*, B 37 (1996) 55-60.
18. T.W. Graham Solomans and C.B. Fryhle, *Organic Chemistry*, (8th ed.), (2004) 153-160, 477.

2006 Copyright ©, International Frequency Sensor Association (IFSA). All rights reserved.

(<http://www.sensorsportal.com>)

The 8th International Symposium on
Measurement Technology and Intelligent Instruments

25-27 September 2007
Tohoku University, Sendai, Japan

Organized by
International Committee on Measurements and Instrumentation (ICMI)
Japan Society for Precision Engineering (JSPE)
Korean Society for Precision Engineering (KSPE)
Chinese Society for Measurement (CSM)
Tohoku University, Research Center for Precision Nanosystems

In cooperation with
UNC Charlotte, Center for Precision Metrology
SIMTech, Singapore Institute of Manufacturing Technology

www.ismtii2007.mech.tohoku.ac.jp

ISMTII 2007

